

# **Process and Apparatus for Minimizing Thermal Gradients Across an Advanced Lithographic Mask**

## **Abstract of the Disclosure**

A method and system to minimize the affects of thermal gradient distortion in reticles. A heat source and filter or filters are used to control which part or parts of the reticle receive additional radiation. The heat created by this additional radiation minimizes any thermal gradients across the mask by supplying a constant heat flux to the entire surface of the mask. The heat source can also be used to preheat the reticle to minimize any transient start-up effects.

## Figures